

AF *IDW*

PATENT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Blees	Examiner:	Kackar, R.
Serial No.:	09/759,179	Group Art Unit:	1763
Filed:	January 12, 2001	Docket No.:	NL 000044 (VLSI.415PA)
Title:	Stamp For Use In A Lithographic Process, Method Of Manufacturing A Stamp, And Method Of Manufacturing A Patterned Layer On A Substrate		

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence and the papers, as described hereinabove, are being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on December 15, 2004.

By: E. M. Nichols
Erin M. Nichols

OFFICE ACTION RESPONSE AFTER FINAL

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the final Office Action dated November 3, 2004, please consider the following remarks.

The pending claims are reflected in the listing of claims beginning at page 2 and the Remarks begin on page 5. No amendments are being presented herewith.